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QUERY CONTROL FORM		RTIS USE ONLY	
Application No.	<u>10/053,576</u>	Prepared by	<u>NPB</u>
Examiner-GAU	<u>Dougherty-2834</u>	Date	<u>2/10/04</u>
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|----------------------|------------------------|--------------------|----------------|
| a. Serial No. | f. Foreign Priority | k. Print Claim(s) | p. PTO-1449 |
| b. Applicant(s) | g. Disclaimer | l. Print Fig. | q. PTOL-85b |
| c. Continuing Data | h. Microfiche Appendix | m. Searched Column | r. Abstract |
| d. PCT | i. Title | n. PTO-270/328 | s. Sheets/Figs |
| e. Domestic Priority | j. Claims Allowed | o. PTO-892 | t. Other |

SPECIFICATION

- a. Page Missing
- b. Text Continuity
- c. Holes through Data
- d. Other Missing Text
- e. Illegible Text
- f. Duplicate Text
- g. Brief Description
- h. Sequence Listing
- i. Appendix
- j. Amendments
- k. Other

MESSAGE

- (1) PTO-1449: Please either initial or line through citations. (copy provided for reference).
- (2) On page 25 of specification, there are two(2) FIG. 58 (b) - no FIG. 58 (a).

please advise.

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CLAIMS

- a. Claim(s) Missing
- b. Improper Dependency
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- g. Amendments
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- k. Other

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RESPONSE

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INFORMATION DISCLOSURE CITATION		ATTY. DOCKET NO. 249-245	SERIAL NO. Unknown			
(Use several sheets if necessary)		APPLICANT TOMONARI et al.	FILING DATE January 24, 2002			
		GROUP 2834				
U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	5,058,856	10/1991	GORDON et al.			
	5,069,419	12/1991	JERMAN			
	5,271,597	12/1993	JERMAN			
	5,059,133	10/1991	HIKAMI et al.			
	5,870,007	2/1999	CARR et al.			
	5,920,417	7/1999	JOHNSON			
	6,044,646	4/2000	SILVERBROOK			
	6,114,794	9/2000	DHULER et al.			
	1,258,368	3/1918	SMITH			
	4,115,750	9/1978	HANSEN et al.			
	6,087,638	7/2000	SILVERBROOK			
	6,124,663	9/2000	HAKE et al.			
FOREIGN PATENT DOCUMENTS						
	DOCUMENT	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
	9-88805	3/1997	JAPAN			
	10-173306	6/1998	JAPAN			
OTHER DOCUMENTS (including Author, Title, Date, Pertinent pages, etc.)						
	"Silicon Microvalves for Gas Flow Control" Phillip W. Barth, Ph.D. Hewlett-Packard Laboratories pp 276-279 The 8 th International Conference on Solid-State Sensors and Actuators, and Eurosensors IX. Stockholm, Sweden, June 25-29, 1995					
	"Electrically-Activated, Micromachined Diaphragm Valves" Hal Jerman IC Sensors Milpitas, CA 95035 pp 363-367					
Examiner*				Date Considered		

Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to application.

Form PTO-FB-A820 (Also PTO-1449)

of the semiconductor microrelay in FIG. 41;

FIG. 50 is a relation drawing used to describe the function of the semiconductor microrelay in FIG. 41;

FIG. 51 is a relation drawing used to describe the function 5 of the semiconductor microrelay in FIG. 41;

FIG. 52 is a partially cutaway view in perspective of the structure of another semiconductor microrelay;

FIG. 53 is a top view to show the structure of a semiconductor microactuator in a related art;

10 FIG. 54 is a sectional view to show the structure of the semiconductor microactuator in the related art;

FIG. 55 is a sectional view to show the structure of a semiconductor microrelay in a related art; and

15 FIG. 56 is a schematic drawing used to describe the function of the semiconductor microrelay in the related art.

FIG. 57 is a partially cutaway view in perspective of the structure of a semiconductor microactuator using a semiconductor device corresponding to another embodiment of the invention;

20 FIG. 58 (b) is a sectional view to show the structure of the semiconductor microactuator in FIG. 57;

FIG. 58(b) is a top view to show the structure of the semiconductor microactuator in FIG. 57;

25 FIG. 59 is a partially cutaway view in perspective of the structure of a semiconductor microactuator using a semiconductor device corresponding to another embodiment of the invention;